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Film deposition on inner surface of tubes using atmospheric pressure argon-acetylene and argon-acetylene-hydrogen plasmas: Interpretation of film properties from plasma-chemical kineticsRamasamy Pothiraja¹, Max Engelhardt¹, Nikita Bibinov¹, Peter Awakowicz¹¹Lehrstuhl AEPT, Ruhr-Universität Bochum, Bochum, Germany

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Hard amorphous hydrocarbon film is deposited on inner surface of glass tubes using filamentary discharge at atmospheric pressure in Ar-C₂H₂-H₂ mixture. Under similar condition, soft film is deposited with high film deposition rate in Ar-C₂H₂ plasma. These differences in film hardness and deposition rate are interpreted on the basis of carbon and hydrogen elemental composition in the plasma systems. Film deposited using Ar-C₂H₂-H₂ mixture shows properties similar to the one deposited using Ar-CH₄ mixture. Film deposition rate is varied along the axis of tubes in Ar-C₂H₂-H₂ mixture. This variation profile can be controlled by controlling the substrate (tube) temperature. Etching efficiency of loosely held carbon with reactive hydrogen atom is studied by varying substrate temperature, and concluded that increasing substrate temperature increases the etching rate. Plasma-chemical kinetics of precursors dissociation and follow-up plasma-chemical reactions are simulated for our experimental conditions using determined plasma parameters. Simulated results are correlated with determined film properties. Plasma parameters are determined using time and space resolved optical emission spectroscopy and laser absorption spectroscopy. Furthermore, the discharge is simulated using nonPDPSIM, which is provided by Mark Kushner. This software allows simulation of discharges at atmospheric pressure and takes the propagation through streamers into account. Discharge parameters like reduced electric field, charged particle densities and electron temperature are simulated and compared to measured data.

References:

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Keywords

Hard amorphous carbon film

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Optical emission spectroscopy and laser absorption spectroscopy

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